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Editors

Ion Beam Modification of Solids

Ion-Solid Interaction and Radiation Damage

Contents

Part I Physical Basics

1	Ion-Solid Interaction	3
	Konrad Gärtner	
1.1	Introduction	3
1.2	Elastic Ion-Atom Interaction	4
1.2.1	Ion-Atom Interaction Potential	5
1.2.2	Scattering Kinematics	8
1.2.3	Scattering Dynamics	10
1.2.4	Scattering Angles and Differential Cross Section	11
1.2.5	Transferred Energy	15
1.3	Inelastic Ion-Atom Interaction	16
1.3.1	High Energy Approach of the Transferred Energy	16
1.3.2	Low Energy Approach of the Transferred Energy	19
1.4	Ion-Amorphous Solid Interaction	22
1.4.1	Scattering Statistics	22
1.4.2	Elastic Energy Loss and Energy Loss Straggling	27
1.4.3	High Energy Inelastic Energy Loss and Energy Straggling	29
1.4.4	Low Energy Inelastic Energy Loss and Energy Straggling	37
1.4.5	Comparison of Stopping Power Theories	41
1.4.6	Energy Loss Distribution	45
1.4.7	Angular Distribution	49
1.4.8	Spatial Distributions of the Ions and the Damage	51
1.5	Ion-Crystalline Solid Interaction	55
1.5.1	Axial Channeling	55
1.5.2	Ion Range and Damage Distribution	58
1.6	Summary	59
	References	60

2	Models for the Description of Track Formation	63
	Christian Dufour and Marcel Toulemonde	
2.1	Introduction	63
2.2	Electronic Energy Deposition	65
2.2.1	Electronic Energy Loss	65
2.2.2	Radial Energy Distribution	66
2.3	Description of Track Formation	69
2.3.1	Coulomb Explosion	70
2.3.2	Bond Weakening (BW) Model	71
2.3.3	Exciton Self-trapping (STX) Model	72
2.3.4	Concept of Reduced Electronic Energy Loss	73
2.3.5	A Transient Thermal Process	75
2.4	Microscopic Models: Molecular Dynamics Approaches	94
2.4.1	Sputtering by Electronic Excitation	95
2.4.2	Track Formation	96
2.4.3	Summary and Conclusions	99
	References	100
3	Modelling Effects of Radiation Damage	105
	William J. Weber and Elke Wendler	
3.1	Introduction	105
3.2	General Remarks	106
3.2.1	Origin of Radiation Damage	106
3.2.2	Sources of Radiation Damage	108
3.2.3	Measurement of Irradiation Damage	109
3.2.4	Quantitative Analysis of Radiation Effects	110
3.3	Modelling of Defect/Damage Accumulation	111
3.3.1	Defect Reaction Rate Theory	112
3.3.2	Effect of Temperature and Diffusion	116
3.3.3	Practical Application	117
3.4	Modelling of Amorphisation and Order-Disorder Phase Transformations	120
3.4.1	Irradiation-Induced Amorphisation Models	120
3.4.2	Amorphisation Kinetics	125
3.5	Modelling of Complex Processes	131
3.6	Summary	134
	References	134
4	Synthesis of Nanostructures Using Ion-Beams: An Overview	137
	Giancarlo Rizza and Mark C. Ridgway	
4.1	Introduction	138
4.2	From Thermodynamic to Driven System	139
4.2.1	Thermodynamic System	139
4.2.2	Kinetic System	143
4.2.3	Driven System	147

4.3	On the Strategies to Synthesize Nanostructures Using Ion-Beams: The Case of Metal-Glass Nanocomposites	151
4.3.1	Ion Implantation	153
4.3.2	Limits and Drawbacks of the Implantation Technique and Some Alternative Approaches	166
4.3.3	Ion Irradiation	169
4.3.4	A Model System to Investigate the Behavior of Nanoparticles Under Irradiation	175
4.4	Conclusion	178
4.5	Appendix: Elementary Processes in Irradiated Solids	179
4.5.1	Principles of Ion-Matter Interaction	179
4.5.2	Defects and Diffusion	180
	References	182

Part II Damage Formation and Amorphization by Nuclear Energy Deposition

5	Primary Processes of Damage Formation in Semiconductors	189
	Elke Wendler and Werner Wesch	
5.1	Introduction	189
5.2	Rutherford Backscattering Spectrometry for Damage Analysis	191
5.2.1	General Considerations	191
5.2.2	Analysis of RBS Aligned Spectra	193
5.3	Continuous Damage Evolution up to Amorphisation	196
5.3.1	Typical RBS Channelling Spectra of Ion Implanted Semiconductors	196
5.3.2	Introduction of Critical Temperatures and Effect of Ion Flux	198
5.3.3	Depth Distribution of Damage and Effect of Ion Energy	205
5.3.4	Fluence Dependence and Effect of Ion Mass	208
5.3.5	Correlation of Damage Cross-Section with Primary Energy Deposition	214
5.4	Discontinuous Damage Evolution up to Amorphisation	217
5.4.1	Damage Formation in AlAs	217
5.4.2	Damage Formation in GaN	224
5.5	Non-amorphisable Materials	229
5.5.1	ZnO	230
5.5.2	CdTe	232
5.6	Summarising Discussion	235
	References	238

6	Damage Formation, Amorphization and Crystallization in Semiconductors at Elevated Temperatures	243
	James S. Williams	
6.1	Introduction	243
6.2	Si Disorder, Amorphization and Crystallisation Processes at Elevated Temperature	245
6.2.1	Dynamic Annealing and Defect Formation During Irradiation	245
6.2.2	Amorphisation Processes at Elevated Temperature	248
6.2.3	Modelling of Ion-Induced Amorphization at Elevated Temperature	250
6.2.4	Ion Beam Induced Epitaxial Crystallisation (IBIEC)	254
6.2.5	IBIEC Models	257
6.3	Irradiation of Ge at Elevated Temperatures	259
6.3.1	Disorder Formation, Amorphization and Ion-Induced Crystallization	259
6.3.2	Formation of Porous Amorphous Layers	261
6.4	Irradiation of GaAs at Elevated Temperatures	264
6.4.1	Disordering and Amorphization	264
6.4.2	IBIIA and IBIEC Processes in GaAs	266
6.5	Other Compound Semiconductors	268
6.5.1	SiC Near and Above T_c	268
6.5.2	IBIIA and IBIEC Behaviour in InP	271
6.5.3	Ternary Semiconductors and Multilayers	272
6.5.4	Unusual Swelling and Erosion Behaviour in Ion Implanted GaN	275
6.5.5	ZnO Microstructure Following Irradiation	279
6.6	Summary and Conclusions	280
	References	283
7	Defect Accumulation, Amorphization and Nanostructure Modification of Ceramics	287
	Yanwen Zhang and William J. Weber	
7.1	Introduction	287
7.2	Energy Deposition Processes in Crystalline Ceramics	289
7.2.1	Damage Production from Atomic Collision Processes	291
7.2.2	Effects of Electronic Energy Loss	291
7.2.3	Coupled Effects of Ionization and Atomic Dynamics	292
7.3	Damage Accumulation	293
7.3.1	Defect Accumulation	293
7.3.2	Irradiation-Induced Phase Transformations	294
7.3.3	Modelling Amorphization	298

7.3.4	Effect of Temperature	300
7.3.5	Effect of Electronic Energy Loss on Amorphization	303
7.4	Ionization-Induced Annealing and Ionization-Enhanced Amorphization	304
7.4.1	Ionization-Induced Annealing: Single Beam Experiments	304
7.4.2	Ion-Induced Annealing: Dual Beam Irradiations	306
7.4.3	Ionization-Enhanced Amorphization	307
7.5	Structural Modifications in Nanostructured Ceramic Matrices	308
7.5.1	Intrinsically Nanolayered Structures	309
7.5.2	Nanocrystalline Materials	311
7.6	Summary	314
	References	315

Part III Damage Formation and Amorphisation by High Electronic Energy Deposition

8	Swift Heavy Ion Irradiation of Crystalline Insulators and Metals	321
	Lionel Thomé	
8.1	Introduction	321
8.2	General Considerations About Electronic Energy Loss in Insulators	322
8.3	Experimental Observation of Electronic Energy Loss Effects	324
8.3.1	Direct Observation of Ion Tracks	324
8.3.2	Indirect Observation of Ion Tracks	327
8.4	Formation of Ion Tracks at Low Fluences	329
8.4.1	Track Formation in Metals and Metallic Compounds	329
8.4.2	Track Formation in Insulators	331
8.5	Structural Transformations at High Fluences	344
8.5.1	Experimental Observations of Structural Transformations	344
8.5.2	Analysis of the Build-Up of Radiation-Induced Structural Transformations with Phenomenological Models	352
8.6	Summary	356
	References	357

9	Swift Heavy Ion Irradiation of Crystalline Semiconductors	365
	Werner Wesch and Claudia S. Schnohr	
9.1	Introduction	365
9.2	Energy Deposition	366
9.3	Track and Damage Formation	369
9.3.1	Materials with High Radiation Resistance	369
9.3.2	Materials with Low Radiation Resistance	376
9.3.3	Threshold Values	384
9.4	Modelling of Track Formation	386
9.4.1	Qualitative Estimations	386
9.4.2	Application of the Inelastic Thermal Spike (i-TS) Model	388
9.5	Summary and Discussion	395
	References	399
10	Swift Heavy Ion Irradiation of Amorphous Semiconductors	403
	Werner Wesch, Tobias Steinbach and Mark C. Ridgway	
10.1	Introduction	403
10.2	Plastic Deformation in Amorphous Materials	404
10.3	Structural Modification in Amorphous Silicon (a-Si)	411
10.3.1	Ion Track Formation in a-Si	411
10.3.2	Plastic Deformation of a-Si	413
10.4	Structural Modification in Amorphous Germanium (a-Ge)	420
10.4.1	Ion Track Formation in a-Ge	420
10.4.2	Porous Layer Formation (Multiple-Ion Irradiation)	424
10.4.3	Plastic Deformation of a-Ge	431
10.4.4	Structural Modification in Other Amorphous Semiconductors	435
10.5	Summary	437
	References	437

Part IV Selected Applications of Ion Irradiation

11	Ion-Shaping of Nanoparticles	443
	Giancarlo Rizza and Mark C. Ridgway	
11.1	Introduction	443
11.2	Ion-Matter Interaction for a Metal-Dielectric Nanocomposite	446
11.3	Influence of the Embedding Matrix	447
11.3.1	Influence of the Ion-Hammering	448
11.3.2	Influence of the Ion Track	449
11.4	Influence of the Nanoparticles	451
11.4.1	Deformation Pathways	453
11.4.2	Kinetics of the Elongation Process	455

11.4.3	Efficiency of the Ion Shaping Process: The Role of the Deposited Energy	458
11.4.4	Elongation as a Function of the Ion Flux	460
11.4.5	Elongation as a Function of the NP Concentration and Stability of the Ion-Shaped NPs	461
11.4.6	Role of Thermodynamics in the Shape Transformation	463
11.5	Toward a Phenomenological Description	464
11.6	Conclusion and Outlook	469
	References	471
12	Low Energy Ion Beam Modification of Nanostructures	475
	Christian Borschel and Carsten Ronning	
12.1	Introduction	475
12.2	Simulations	477
12.3	Enhanced Dynamic Annealing in Nanostructures	482
12.4	Semiconductor Nanowires	484
12.4.1	Ion Beam Doping	485
12.4.2	Damage Profiles and Bending of Nanowires	489
12.5	Sputtering of Nanostructures	491
12.5.1	Static Sputtering Calculations	492
12.5.2	Dynamic Sputtering Calculations	494
12.6	Summary	497
	References	498
13	Modification of Structure and Properties of Optical Crystals	501
	Feng Chen and Frank Schrempel	
13.1	Introduction	501
13.2	Ion Beam Induced Damage and its Effects in Optical Crystals	502
13.2.1	Damage Formation Due to Nuclear Energy Deposition	502
13.2.2	Damage Formation Due to High Electronic Energy Deposition	506
13.3	Methods for the Production of Optical Elements Based on Crystal Damage	509
13.3.1	Refractive Index Modulation and Waveguides	510
13.3.2	Crystal Ion Slicing (CIS)	512
13.3.3	Ion Beam Enhanced Etching (IBEE)	514
13.4	Application of Ion Beam Induced Effects for the Production of Optical Elements	517
13.4.1	Electro-optical Modulators	517
13.4.2	Guided-Wave Frequency Doublers	518

13.4.3 Waveguide Lasers	520
13.4.4 3D Optical Micro- and Nanostructures	523
13.5 Summary	524
References	525
Index	529